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PATENT  
3430-0149P

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1/31/03

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicants: Jeong-Jin KIM et al.

Conf.: 5548

Serial No.: 09/727,516

Group: 1765

Filed: December 4, 2000

Examiner: V. Ramos

For: APPARATUS FOR AND METHOD OF ETCHING AND CLEANING  
OBJECTS

**RESPONSE TO EXAMINER'S RESTRICTION REQUIREMENT**

Assistant Commissioner for Patents  
Washington, DC 20231

January 28, 2003

Sir:

In response to the Examiner's Restriction Requirement dated January 13, 2003, the following election and remarks are respectfully submitted in connection with the above-identified application.

**IN THE CLAIMS:**

Applicants hereby elect Group II consisting of claims 4-11 for initial examination in this application. This election is with traverse.

**REMARKS**

Applicants thank the Examiner for the thorough consideration given the present application. Claims 1-11 are currently being prosecuted. The Examiner